

**Notice of References Cited**

Application/Control No.

10/822,373

Applicant(s)/Patent Under  
Reexamination  
YAMANAKA ET AL.

Examiner

Kezhen Shen

Art Unit

2627

Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-2005/0111310 A1	05-2005	Kobayashi et al.	369/013.14
*	B	US-6,038,208	03-2000	Shikunami et al.	369/275.3
*	C	US-2004/0208101	10-2004	Ohkubo et al.	369/053.35
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Ogawa, Masatsugu et al., Optimication of Write Conditions with a New Measure in High-Density Optical Recording, July 29 2004, Japanese journal of Applied Physics, Vol. 43, No. 7B, pp 4863-4866
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.